



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **WATANABE, Kenichi**

Group Art Unit: **2815**

Serial No.: **09/987,012**

Examiner: **Chris C. Chu**

Filed: **November 13, 2001**

P.T.O. Confirmation No.: 6363

For: **SEMICONDUCTOR WAFER DEVICE HAVING SEPARATED CONDUCTIVE PATTERNS IN PERIPHERAL AREA AND ITS MANUFACTURING METHOD**

RESPONSE UNDER 37 CFR §1.116
- EXPEDITED RESPONSE -
GROUP ART UNIT 2815

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 12, 2003

Sir:

In response to the Office Action dated **August 1, 2003**, extended to **December 1, 2003** by
a **one (1)** month Petition for Extension of Time, please amend the above-identified application as
follows:

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